

UNITED STATES PATENT AND TRADEMARK OFFICE  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 6,820,676 B2  
DATED : November 23, 2004  
INVENTOR(S) : Julio C. Palmaz et al.

Page 1 of 2

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Title page,

Item [62], **Related US. Application Data**, please delete "09/433,929" and insert -- 09/443,929 -- please delete "November 4, 1999" and insert -- November 19, 1999 --.

Item [56], **References Cited**, U.S. PATENT DOCUMENTS, please delete "Inoue" and insert -- Inoue --; and please insert -- U.S. Patent No. 5,649,951, issued 7/22/1997 to Davidson, U.S. Classification 606/198 --;

-- U.S. Patent No. 6,013,855, issued 1/11/2000 to McPherson, et al., U.S. Classification 623/23.76 --; and -- U.S. Patent No. 5,329,514, issued 7/12/1994 to Euguchi, et al., U.S. Classification 369/126 --.

FOREIGN PATENT DOCUMENTS, please insert -- German Patent No. 1452370, issued 21 March 1974, International Classification C21C 37/15 --; and -- European Patent No. 0 400 947, issued 29 May 1990, International Classification C23C 16/00 --.

**OTHER PUBLICATIONS,**

"Focused Ion Beam NonaFabrication" reference, please delete

"<http://www.glue.umd.edu/~astan/avs04.htm>" and insert

-- <http://www.glue.umd.edu/~astan/av04.htm> --.

"Amorphous Carbon and C:N Thin Films" reference, please delete

"<http://www.glue.umd.edu/~astan/av61.htm>" and insert

-- <http://www.glue.umd.edu/~astan/av01.htm> --.

"Multilayer Ceramic/Metallic Coatings by Ion Beam-Assisted," reference, please delete

"Deposition" and insert -- Deposition --; and please delete the second instance of "Applied Research".

"Biocompatibility of Cardiac Cells on Silane-Modified Surfaces" reference, please delete

"45th" and insert -- 46th --.

"Biofunctionalization of Surfaces with Peptide Amphiphiles" reference, please delete

"Amphiphiles" and insert -- Amphiphiles --.

"Plasma Co-polymer Surfaces for the Controlled Adsorption of Common Proteins"

reference, please delete "October 19, 1999" and insert -- October 29, 1999 --.

"The influence of ion radiation..." reference, please delete "radiation" and insert

-- irradiation --.

"Sputtering Targets High-Quality Thin Film Materials" reference, please delete "Ametek"

and insert -- AMETEK --.

"Endothelial Cell Organization of Micropatterned Protein Surfaces" reference, please

delete "of" and insert -- on --.

"Sputter-deposition of TiNi," reference, please delete "E. Quandt" and insert -- E. Quandt, et al. --.

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Title page (cont'd),

Please delete "Thin Film Shape Memory Microwaves with Adjustable Operation Temperature" by M. Kohl, D. Kittmann, E. Quandt, and B. Winzek, *Sensors and Actuators*, vol. 83, pp. 214-219 (2000)".

"Liquid Sources for Chemical Vapor Deposition..." reference, please delete "cgl" and insert -- cgi --.

"Risk Analysis of Stents With a Diamond-Like..." reference, please delete "pp. 1-5" and insert -- pp. 1-6 --.

Please delete "Thin Film Shape Memory Alloy Microactuators" by TiNi Alloy Company (online)".

Please delete "Progress in Thin Film Shape Microactuators" by Johnson, et al., [www.sma-mems.com/recent.htm](http://www.sma-mems.com/recent.htm) (Overview), pp. 1-6".

Please delete "The influence of ion irradiation during film growth on the chemical stability of film/substrate systems" by W. Ensinger, *Surface and Coatings Technology*, vol. 80, pp. 35-48 (1996)".

Column 9,

Line 9, please delete "endolumina)" and insert -- endoluminal --.

Line 12, please delete "endoluntinal" and insert -- endoluminal --.

Line 14, please delete "iniplantable" and insert -- implantable --.

Line 14, please delete "endoiwninal" and insert -- endoluminal --.

Column 10,

Line 13, please delete "the," and insert -- the --.

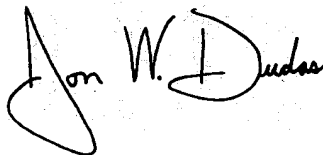
Line 15, please delete "nm/sec." and insert -- nm/sec, --.

Line 20, please delete "stens" and insert -- steps --.

Line 20, please delete "layer:" and insert -- layer; --.

Signed and Sealed this

Fifteenth Day of November, 2005



JON W. DUDAS

Director of the United States Patent and Trademark Office